



Tool Make & Model

KLA / SPTS - OMEGA fxP

Tool Configuration / Specifications

Plasma Etcher

Rapier

APS

ICP

PRS Chm

Excluded:

ESA70W Pump (QTY 1)

ESR20N Pumps (QTY 1)

Helium MFM for ICP Module Missing (QTY 1)

Software Version - 12.5.1

Process - Si/Ox/ Nit Etch

Chamber System:

- Rapier Module
- APS Module
- PRS Module
- ICP Module

Handler System - VCE (QTY 2)

RF & Power Rack (QTY 2)

VSP

Browse our site at www.moov.co

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